



# **A Practical Approach for Low-Cost Hermetic Lid Sealing**

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# Outline

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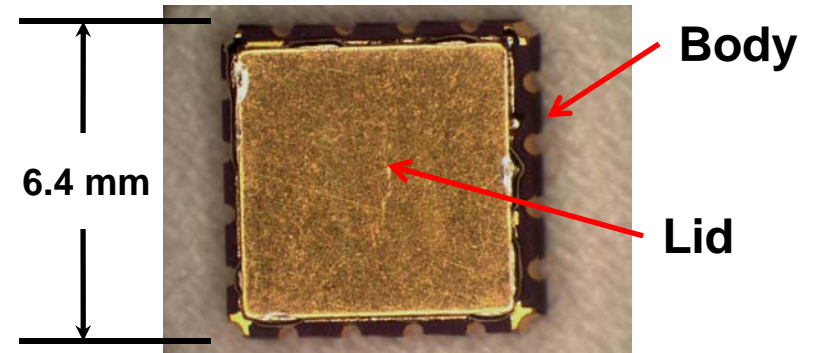
- **Motivation**
- **Material system**
- **Bench top reflow equipment and lid seal process**
- **LCC reflow experiment**
- **Results**
- **Discussion: comparing reflow platforms**
- **Conclusions and future work**



# Motivation

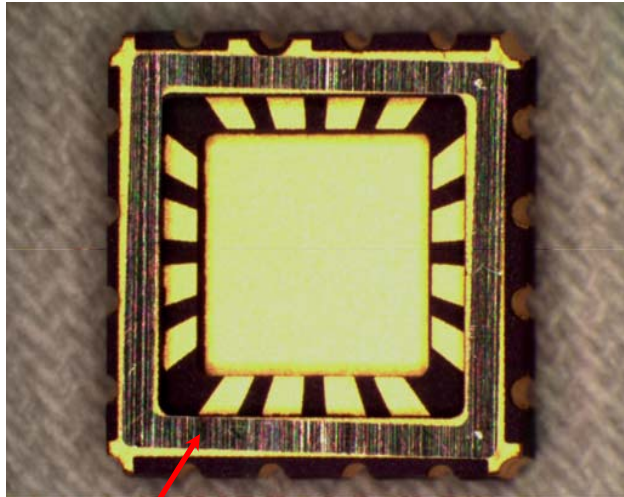
- Surface mount leadless chip carrier (LCC)
- Hermetically sealed by reflow of a lead-free solder pre-form
- Large belt-style reflow furnace
  - Mass production of PCBs with surface mount devices
  - 30 to 45-minute cycle time
  - Peak input temperature above 350°C
- An enterprise that assembles low-volume, hermetic LCCs desires:
  - Compact equipment
  - Lower acquisition cost
  - Lesser cycle time
  - Lower energy consumption

Can a practical, low-volume lid seal process with measurable attributes be adapted to compact reflow equipment?





# Material System

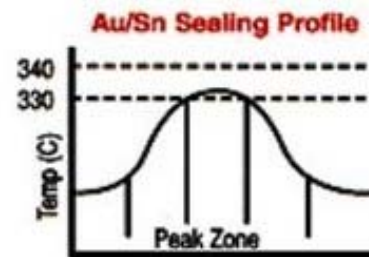
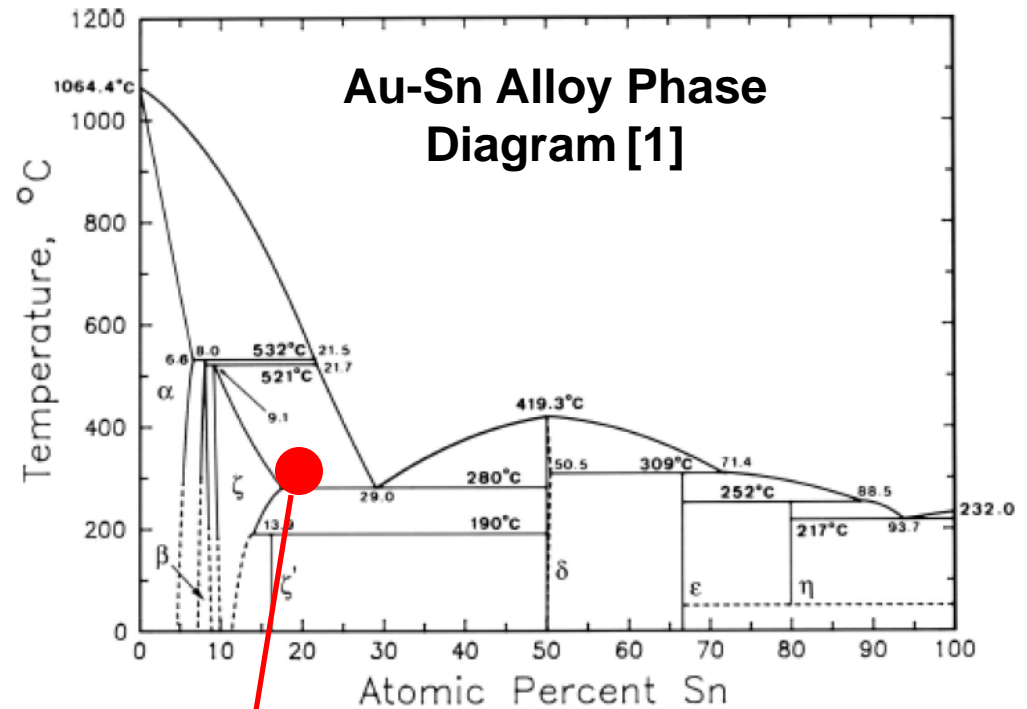


- 80Au-20Sn solder pre-form tacked to lid
- High-temperature co-fired ceramic (HTCC) body
- Seal ring plated with 60  $\mu$ m Au on Ni
- Kovar lid with Ni-Au plating

## References:

<sup>1</sup> *Processing and Reliability Issues for Eutectic AuSn Solder Joints* in Proceedings 41<sup>st</sup> International Symposium on Microelectronics (IMAPS 2008), pp. 909-916.

<sup>2</sup> Materion Corp. ([www.materion.com](http://www.materion.com)).

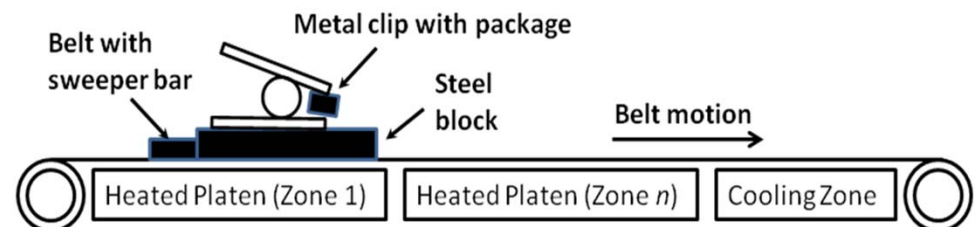
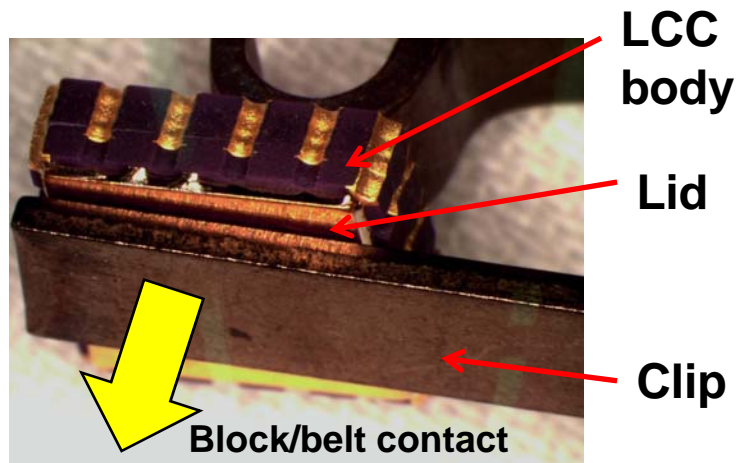


**2-5 minutes  
above 280°C [2]**



# Bench Top Reflow Equipment and Lid Seal Process

- Compact dual-mode conduction/convection reflow furnace:
  - 1.2-meter long conveyor
  - Four programmable conduction heating zones
  - Four programmable convection heating zones overhead
  - Cooling stages follow conduction/convection zones.
  - Convection zones flow heated  $N_2$  at 40 sccf/h.
  - Variable gap between opposing zones
- Traditionally for for ball attach and surface mount operations.
- Multiple LCCs oriented horizontally and arranged in parallel on metal block.
- Metal clips hold an Au-plated A42 lid with solder pre-form against package frame.
- Configured with lid facing downward for greater conduction to pre-form.





# LCC Reflow Experiment

- **Desired profile: greater than 280°C for five minutes max., peak temperature 320°C.**
- **Seven process trials (three parallel LCC samples per trial)**
- **Compiled a temperature history for each run.**
- **Sealed packages underwent visual and x-ray inspection of the seal area**
- **Fine and gross leak tests per MIL-STD-883G, Method 1014.2**

<b>Trial</b>	<b>Conduction Zone Temps (°C)</b>	<b>Convection Zone Temps (°C)</b>	<b>Conveyor Velocity (mm/s)</b>
1	200-280-375-375	175-245-320-332	2.96
2	200-280-375-375	175-245-320-332	2.54
3	200-280-360-360	175-245-320-332	2.54
4	200-280-350-350	175-245-320-332	2.54
5	200-280-340-340	175-245-300-315	2.12
6	200-280-340-340	175-245-300-315	2.54
7	200-280-340-340	200-230-340-340	2.12

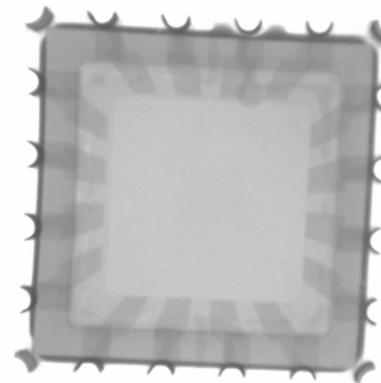
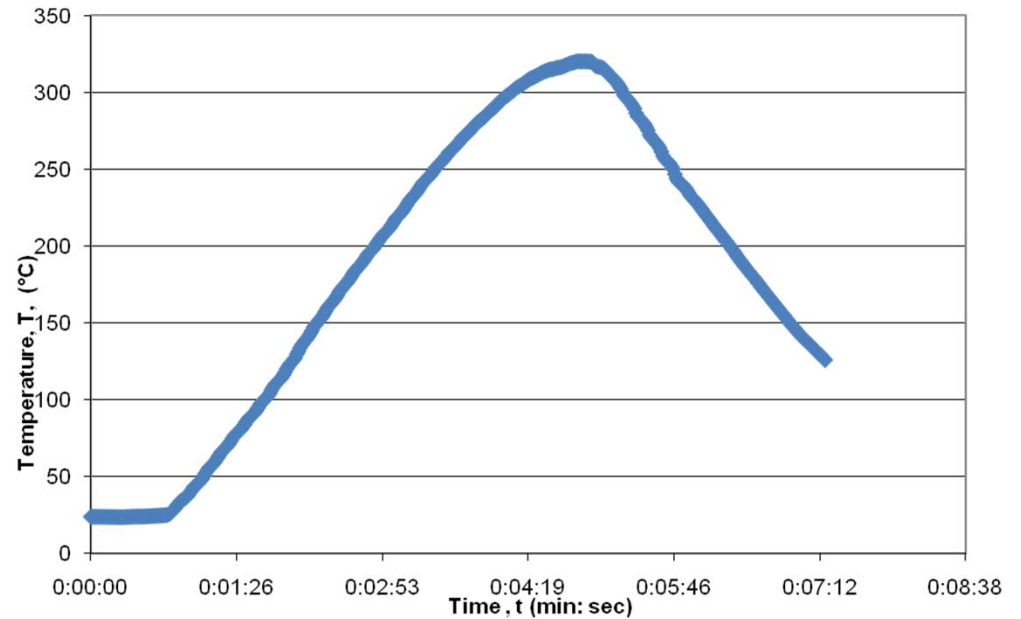
**Trials were run with the compact furnace to identify the reflow recipe that yields the prescribed peak temperature profile, a structurally-sound hermetic lid seal, and the lowest cycle time.**



## Results

- 84% reduction in cycle time
- Peak temperature: 320°C.
- Void-free fillet
- Greatest leak rate observed was  $1.3 \times 10^{-9}$  atm-cm<sup>3</sup>/s.
- Standard:  $9 \times 10^{-8}$  atm-cm<sup>3</sup>/s after 60 seconds.

Trial	Cycle Time (min: sec)	Peak Temp at LCC Lid (°C)
1	6:08	298
2	6:53	335
3	6:59	325
<b>4</b>	<b>7:15</b>	<b>320</b>
5	8:39	320
6	6:59	315
7	8:45	330

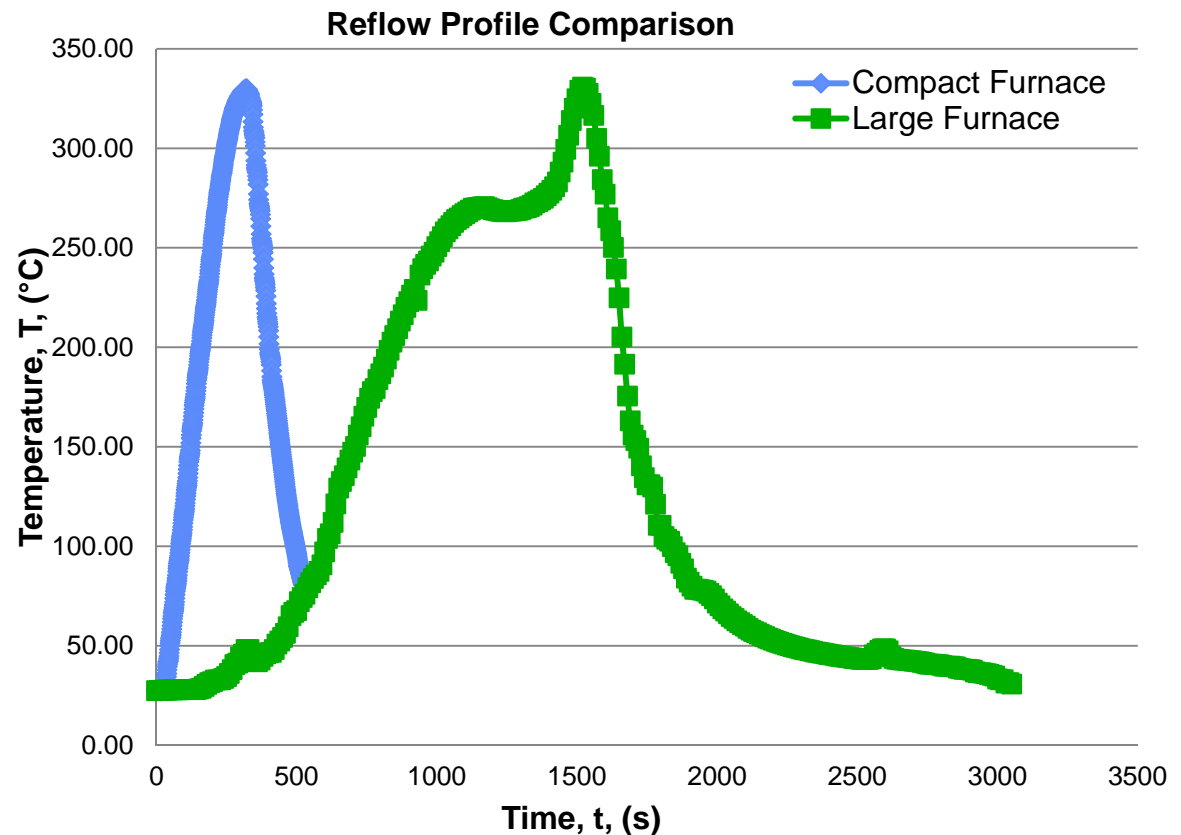






# Comparing Reflow Platforms

- **Large belt-style reflow furnace:**
  - High throughput
  - Stable, repeatable
- **Compact bench top system:**
  - Lesser cycle time, greater productivity, lower labor cost
  - Lower capital investment (approximately \$25k US)
  - Lower peak input temperatures
  - More zones, higher rate of heat transfer



**Trade throughput for lesser cycle time.**





## Conclusions and Future Work

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- **Hermetic lid sealing in this example is possible with the compact, dual-mode conduction/convection reflow furnace in a fraction of the cycle time relative to the larger apparatus.**
- **Actual peak temperature closer to control input**
- **Future work:**
  - **Impact of peak reflow temperature on device functionality, e.g. GaAs thermally-activated “sinking gates”<sup>1</sup>**
  - **Measure true temperature at the lid seal.**
  - **Investigate repeatability.**
  - **Measure energy consumption.**

**Reference:**

<sup>1</sup>Canali, C., et al., “Gate metallization “Sinking” into the active channel in Ti/W/Au metallized power MESFET’s,” Electron Device Letters, 7 (3), 1986, pp. 185-187.